## Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

- 1-14. (Canceled)
- 15. (Currently Amended) A semiconductor device comprising:
  - a semiconductor chip;
  - a substrate on which a interconnecting pattern is formed; and
- a binder electrically connecting the semiconductor chip and the interconnecting pattern, the binder including:
  - a first-layer; layer including a first resin; and
- a second layer <u>including conductive particles dispersed only in a second</u> resin, the second layer being disposed closer to the substrate than the first layer, a coefficient of thermal expansion of the first <u>layer-resin</u> being smaller than a coefficient of thermal expansion of the second resin.
- 16. (Original) The semiconductor device as defined in Claim 15, wherein the binder is an anisotropic conductive film.
  - 17-18. (Canceled)
- 19. (Previously Presented) A circuit board on which the semiconductor device as defined in Claim 15 is mounted.
- 20. (Presently Presented) Electronic equipment comprising the semiconductor device as defined in Claim 15.
  - 21-28. (Canceled)
- 29. (Previously Presented) The semiconductor device as defined in Claim 15, wherein a silica insulating filler is mixed only in the first layer.

- 30. (Previously Presented) The semiconductor device as defined in Claim 15, wherein the second layer includes an epoxy resin.
- 31. (Previously Presented) The semiconductor device as defined in Claim 15, wherein conductive particles are dispersed only in the second layer.
- 32. (Previously Presented) The semiconductor device as defined in Claim 15, wherein the conductive particles are dispersed only in the second layer: and wherein the second layer is thinner than the first layer, and the second layer has higher viscosity than the first layer when melted.
- 33. (Currently Amended) The semiconductor device as defined in Claim 15, wherein a silica insulating filler is mixed only-in the second-first layer.
- 34. (Currently Amended) The semiconductor device as defined in Claim 15, wherein a silica insulating filler is mixed in the first layer and the second layer, and a component ratio of the silica insulating filler in the second-first layer is greater than a component ratio of the silica insulating filler in the first-second layer.
- 35. (Currently Amended) The semiconductor device as defined in Claim 15, wherein a molecular weight of the second layer is greater than a molecular weight of the first layer at least the first resin including an epoxy resin.
- 36. (Currently Amended) A semiconductor device comprising:
  - a semiconductor chip;
- a substrate on which a interconnecting pattern is formed; and a binder electrically connecting the semiconductor chip and the interconnecting pattern, the binder including:
  - a first-layer; layer including a first resin; and

a second layer <u>including conductive particles dispersed only in a second resin</u>, the second layer being disposed closer to the substrate than the first layer, wherein a modulus of elasticity of the second <u>layer is resin being</u> smaller than a modulus of elasticity of the first <u>layer-resin</u>.

- 37. (Previously Presented) The semiconductor device as defined in Claim 36, wherein the binder is an anisotropic conductive film.
- 38. (Previously Presented) The semiconductor device as defined in Claim 36, wherein a coefficient of thermal expansion of the first layer is smaller than a coefficient of thermal expansion of the second layer.
- 39. (Previously Presented) The semiconductor device as defined in Claim 36, wherein a silica insulating filler is mixed only in the first resin.
- 40. (Previously Presented) The semiconductor device as defined in Claim 36, wherein a silica insulating filler is mixed in the first layer and the second layer, and a component ratio of the silica insulating filler in the first layer is greater than a component ratio of the silica insulating filler in the second layer.
- 41. (Previously Presented) The semiconductor device as defined in Claim 36, wherein the second resin includes an epoxy resin.
- 42. (Previously Presented) The semiconductor device as defined in Claim 36, wherein conductive particles are dispersed only in the second layer; and wherein the second layer is thinner than the first layer, and the second layer has higher viscosity than the first layer when melted.
- 43. (Currently Amended) The semiconductor device as defined in Claim 36, wherein a molecular-weight of the second layer is greater than a molecular weight of the first layer the first resin including an epoxy resin and the second resin including a biphenyl resin.

- 44. (Previously Presented) A circuit board on which the semiconductor device as defined in Claim 36 is mounted.
- 45. (Previously Presented) Electronic equipment comprising the semiconductor device as defined in Claim 36.

46-49. (Canceled)